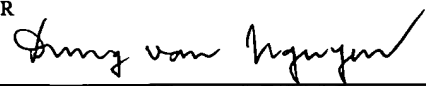
 <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> Form PTO-1449 (Modified) (Use several sheets if necessary)				<b>COMPLETE IF KNOWN</b>	
				Application Number	09/651,779
				Confirmation Number	2448
				Filing Date	August 30, 2000
				First Named Inventor	Scott E. Moore
				Group Art Unit	3723
				Examiner Name	Dung V. Nguyen
Sheet	1	of	1	Attorney Docket No.	108298515US

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		NUMBER	Kind Code (if known)			
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		Office	NUMBER	Kind Code (if known)				

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T
DVN	AG	KONDO, S. et al., "Abrasive-Free Polishing for Copper Damascene Interconnection," <i>Journal of the Electrochemical Society</i> , Vol. 147, No. 10, pp. 3907-3913, The Electrochemical Society, Inc., Pennington, New Jersey, 2000. ✓	
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EXAMINER 	DATE CONSIDERED 4-21-2003
*EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application(s).	